

FIG. 1.

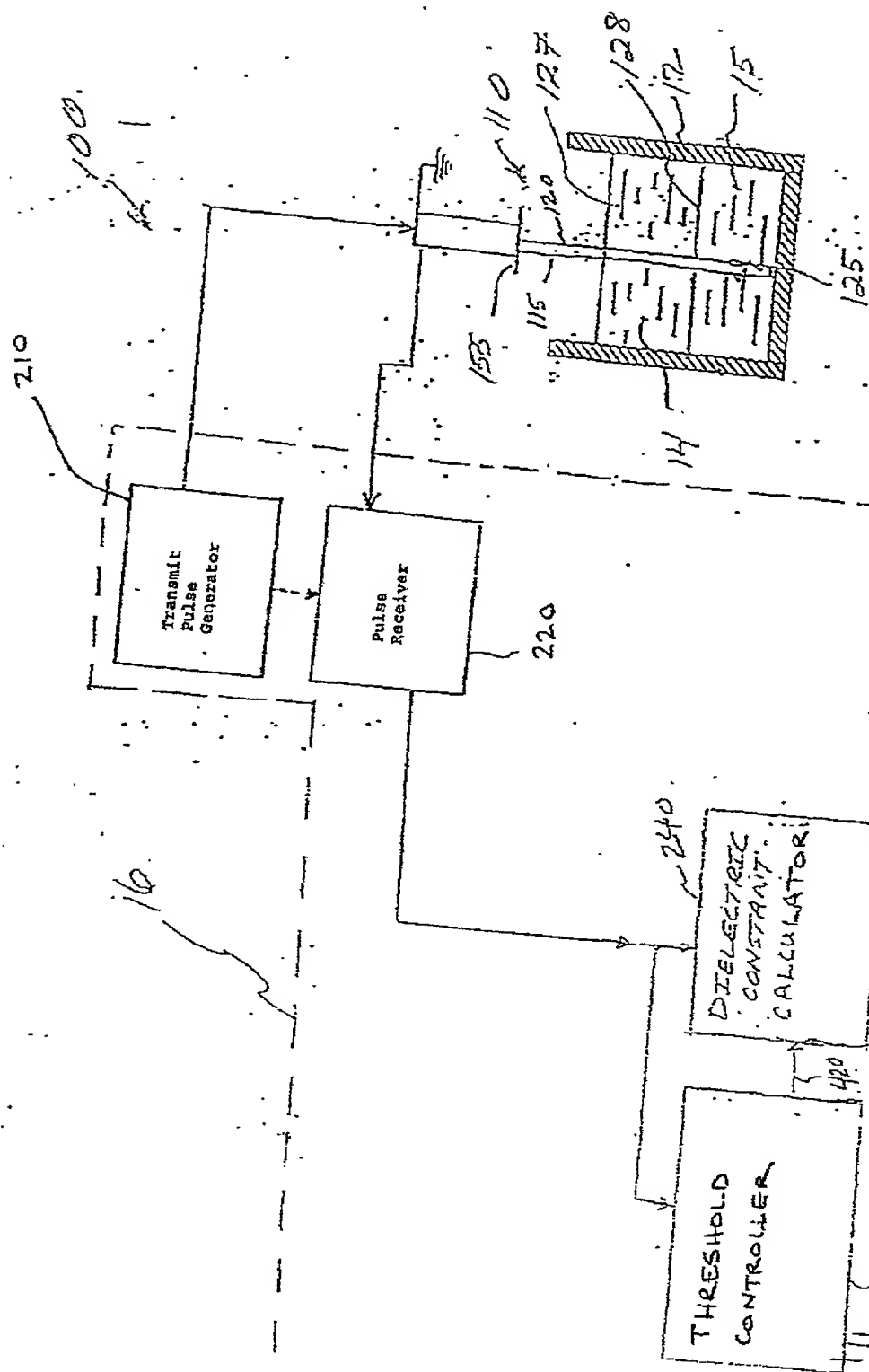


FIG. 2

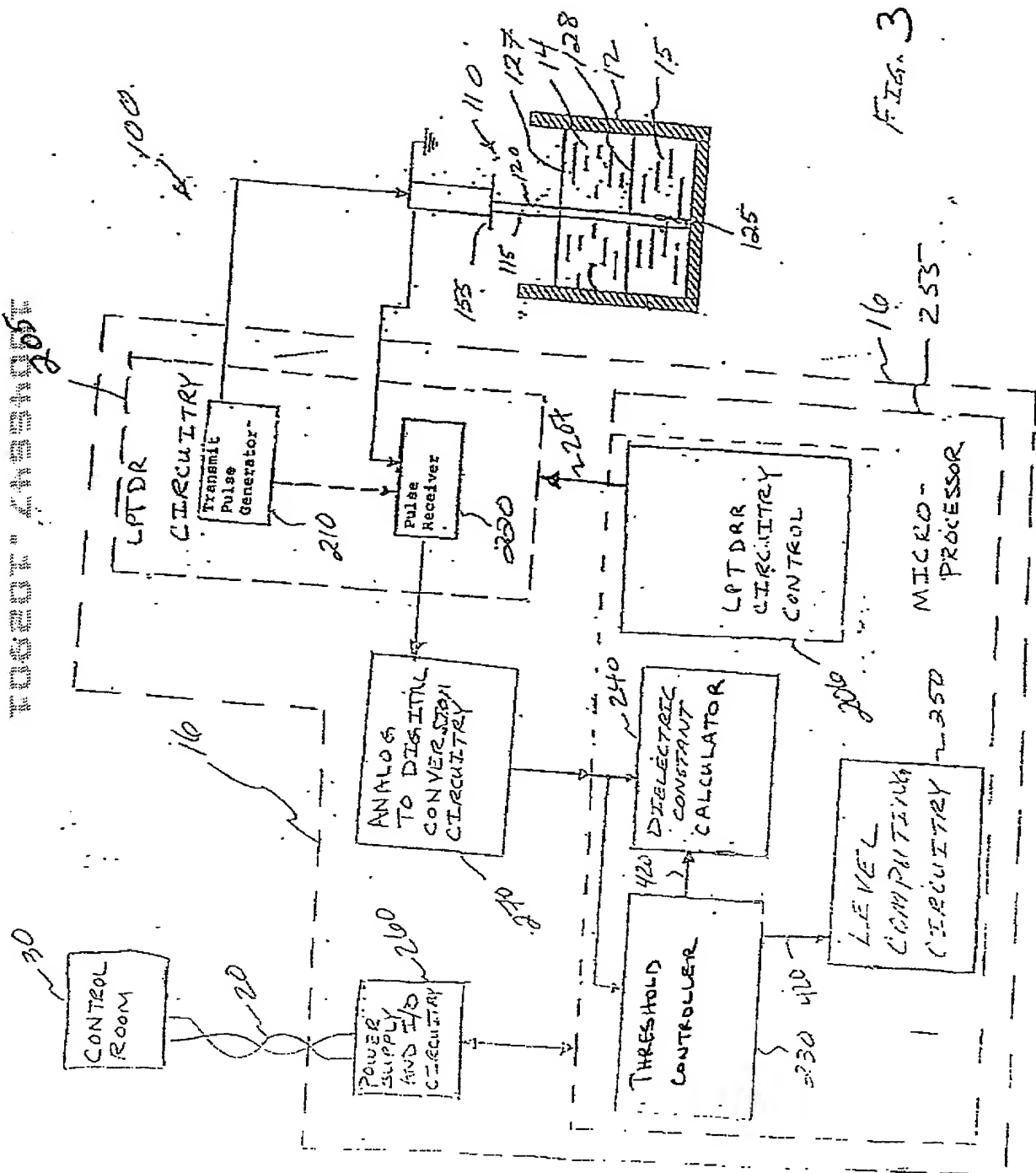


FIG. 3

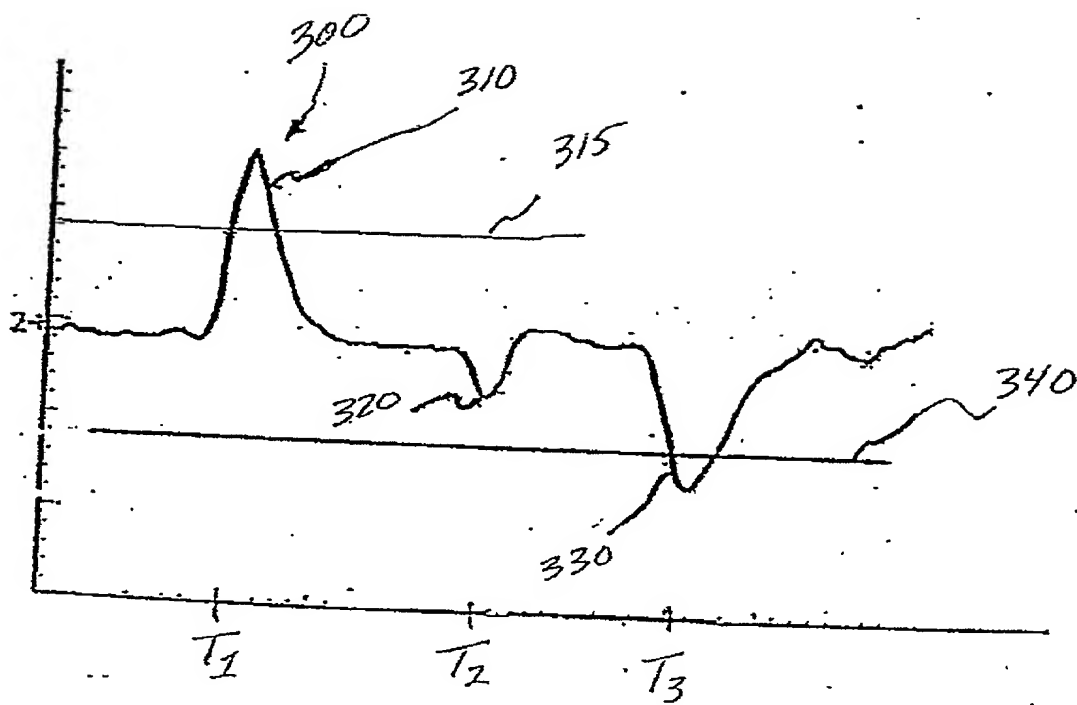


FIG. 4

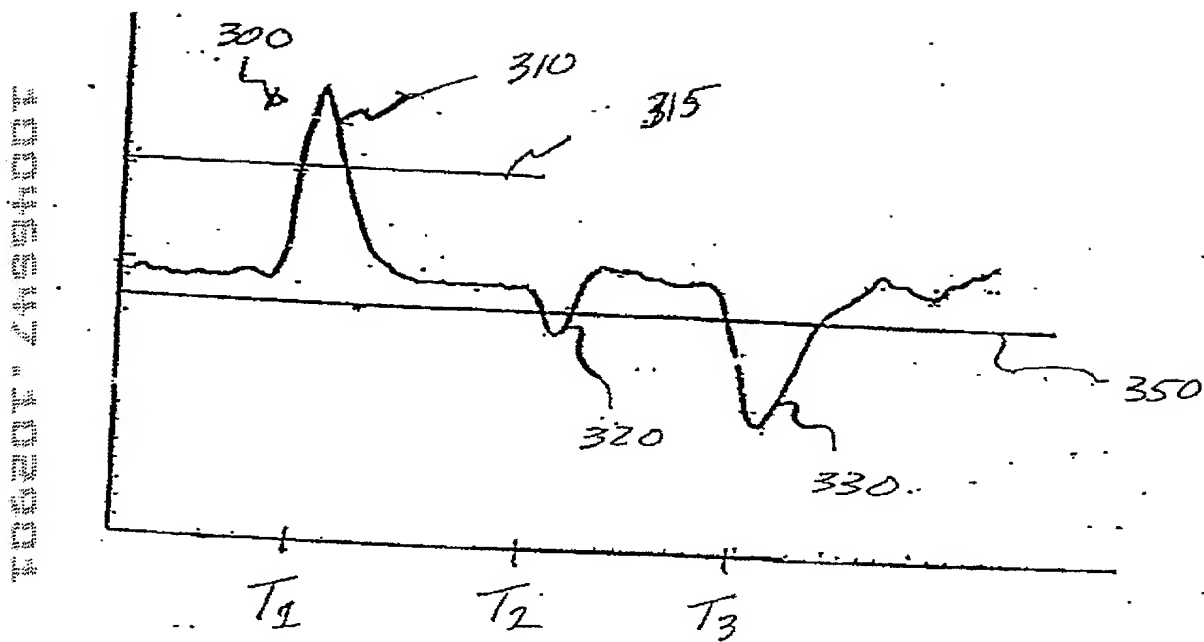


FIG. 5

FIG. 6

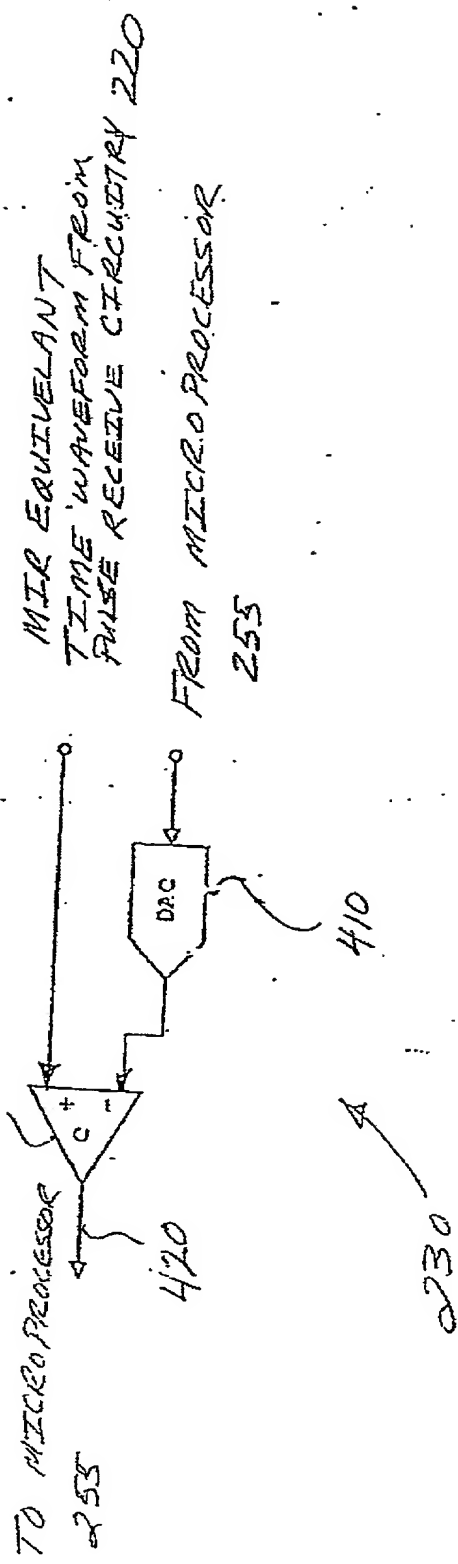


FIG. 6

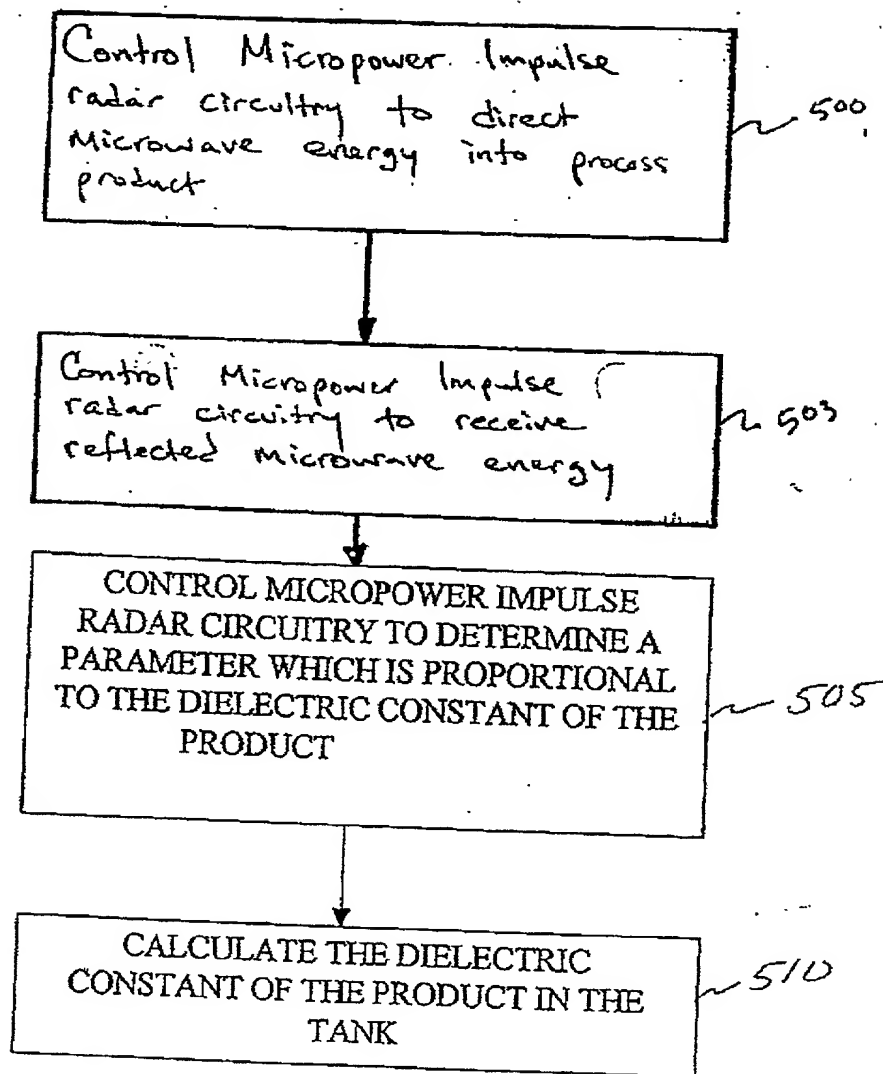


FIG. 7

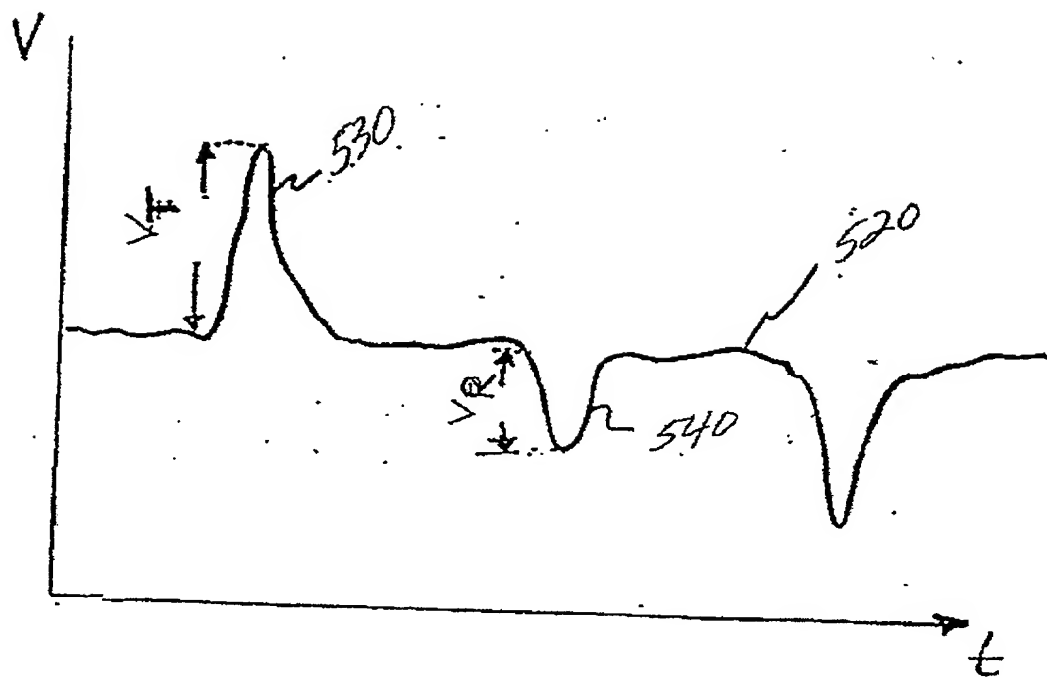


FIG. 8



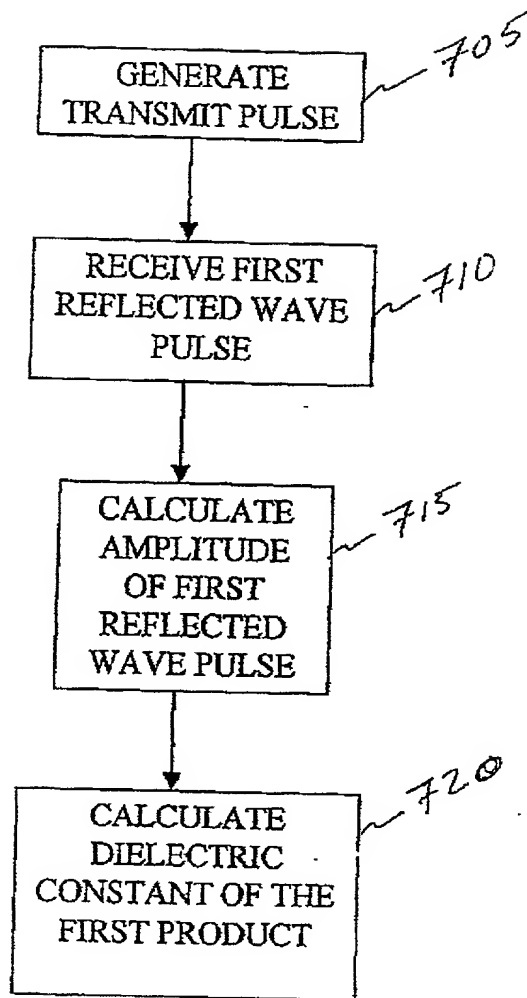


FIG. 9

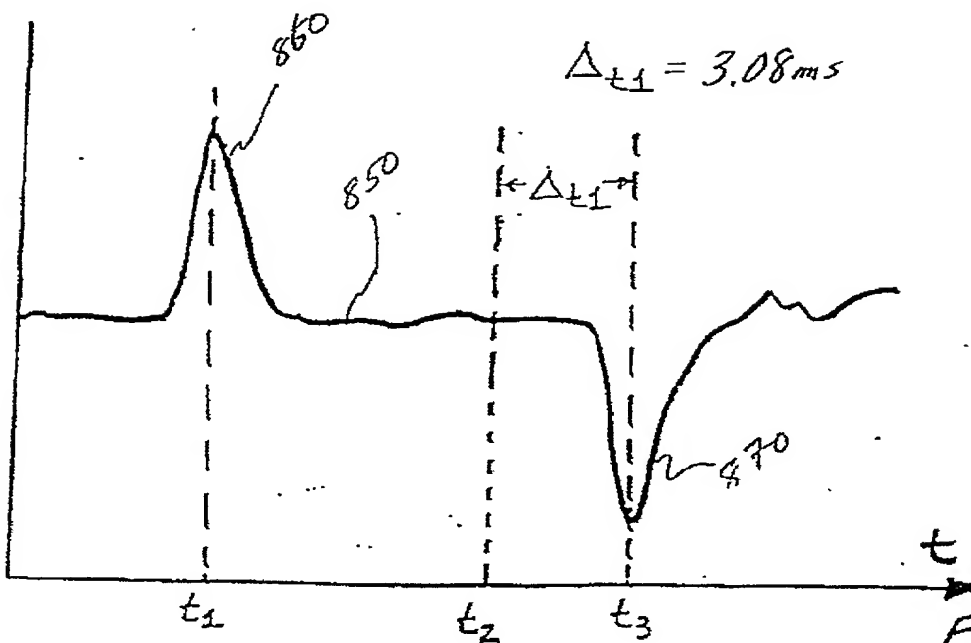


FIG. 10

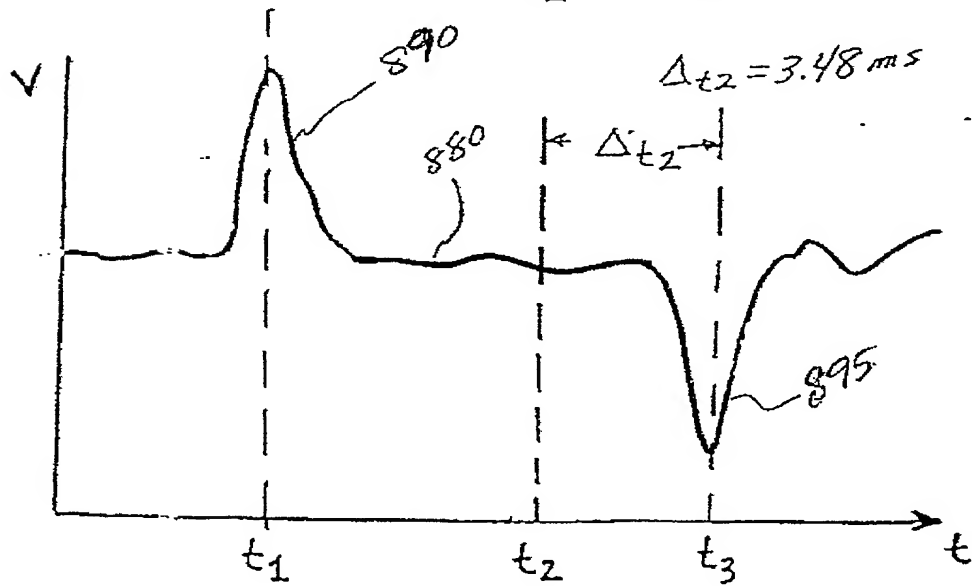


FIG. 11

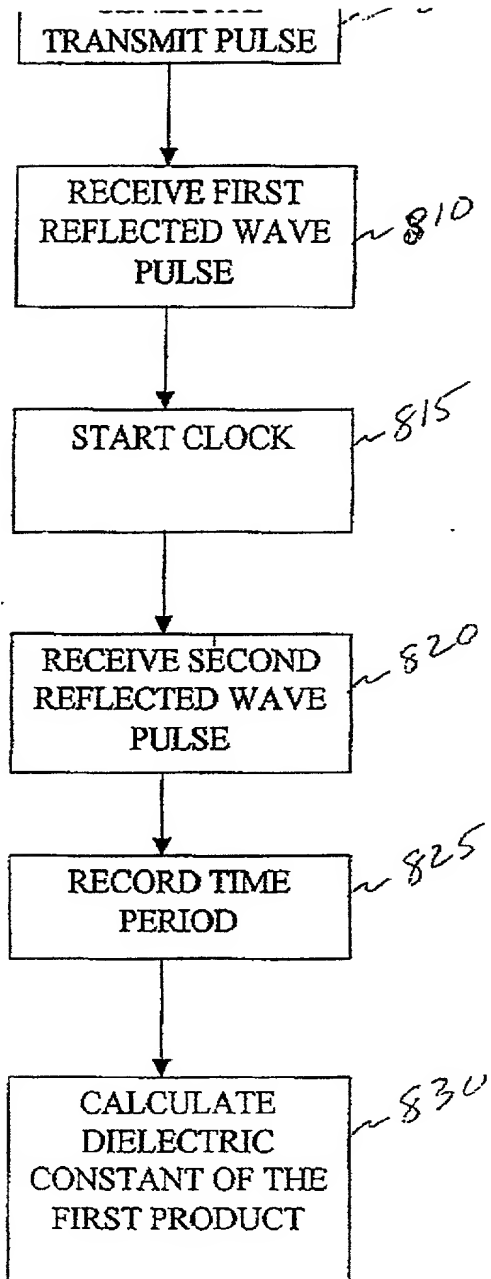
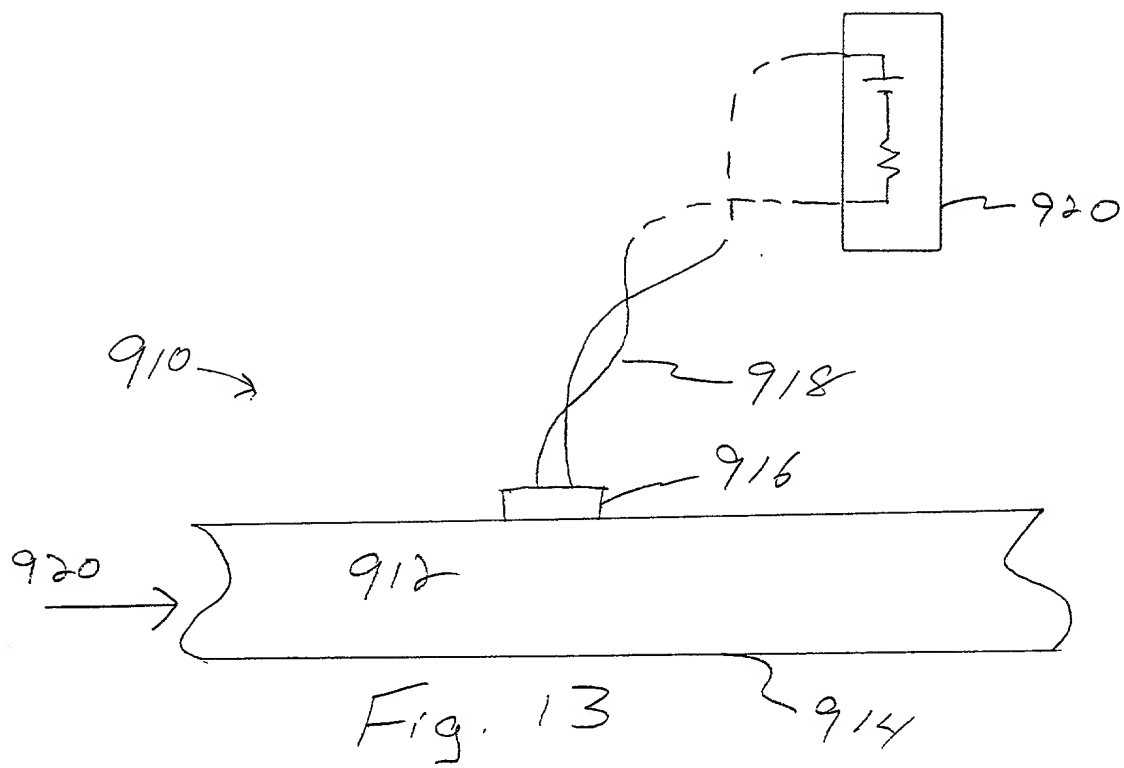


FIG. 12



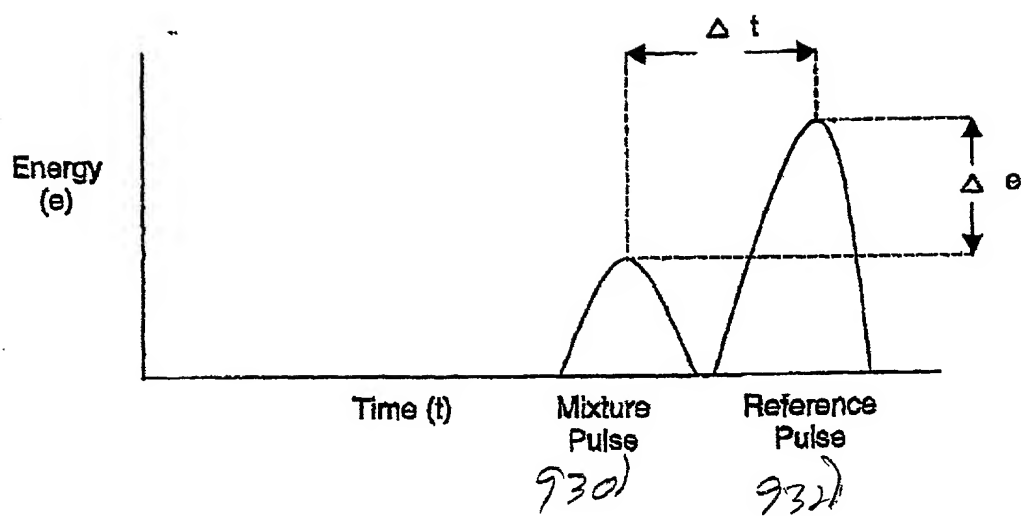


Fig. 14

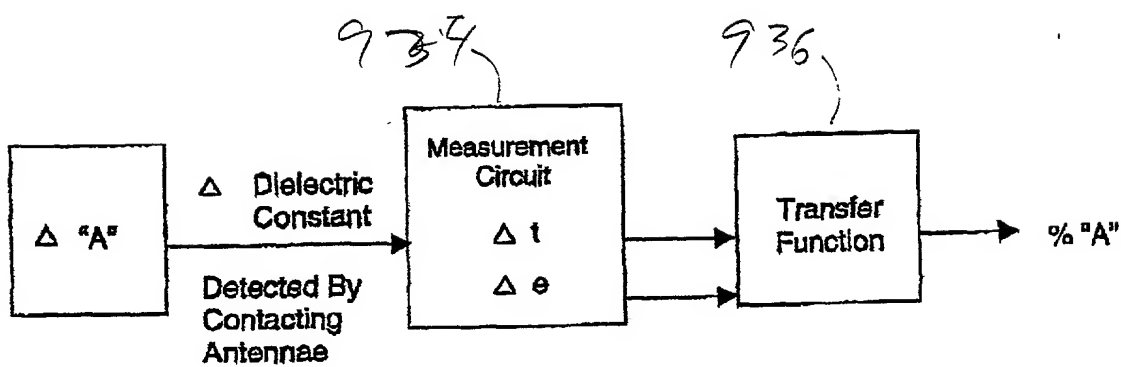


Fig. 15

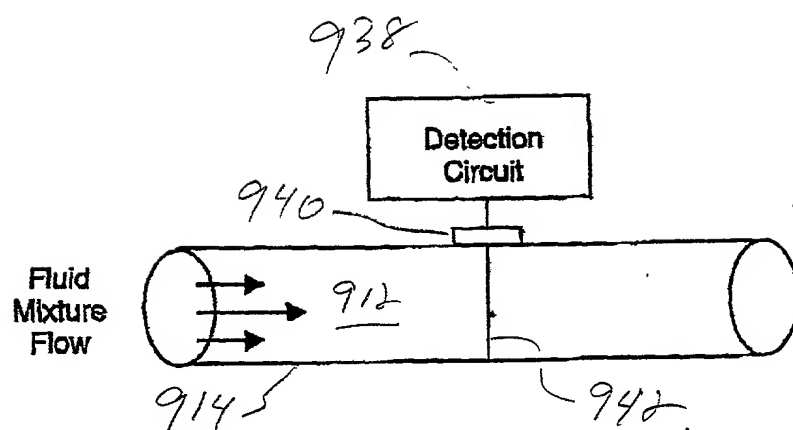


Fig. 16

FIG. 17 is a schematic diagram of a device 1000.

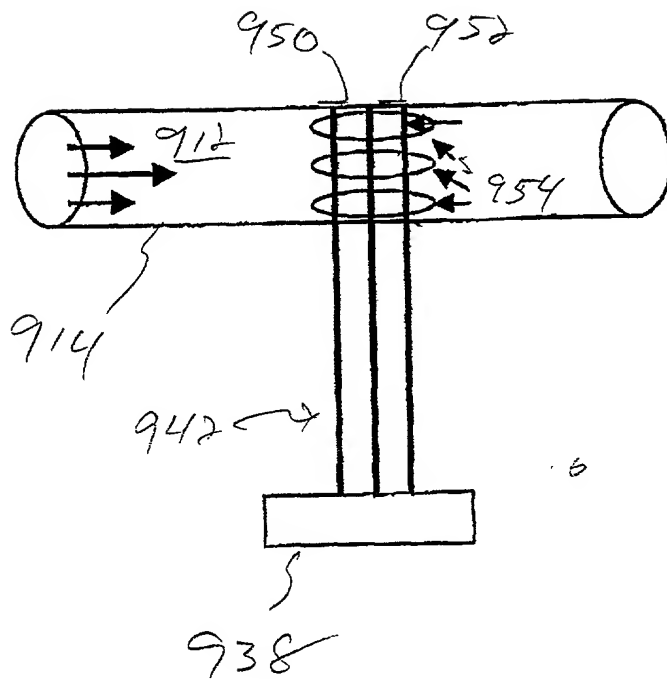


Fig. 17





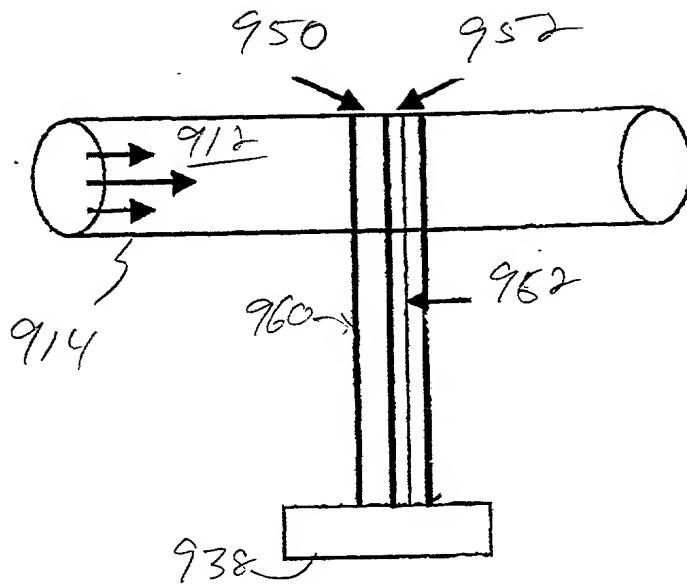


Fig. 19

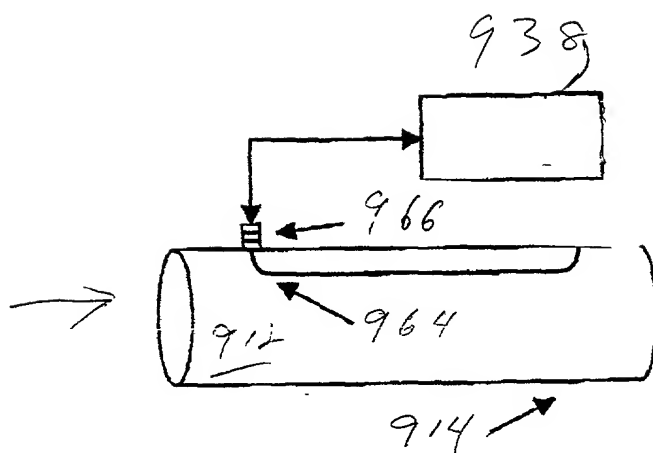


FIG. 20

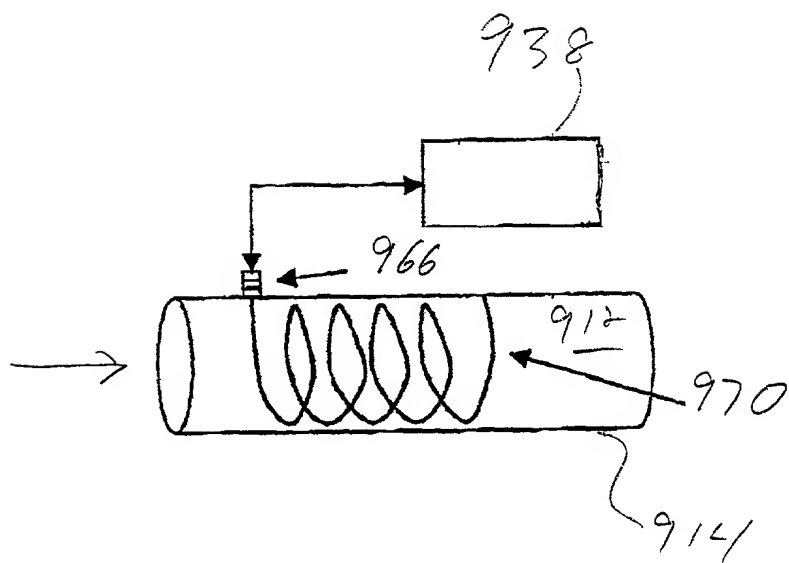


Fig. 21

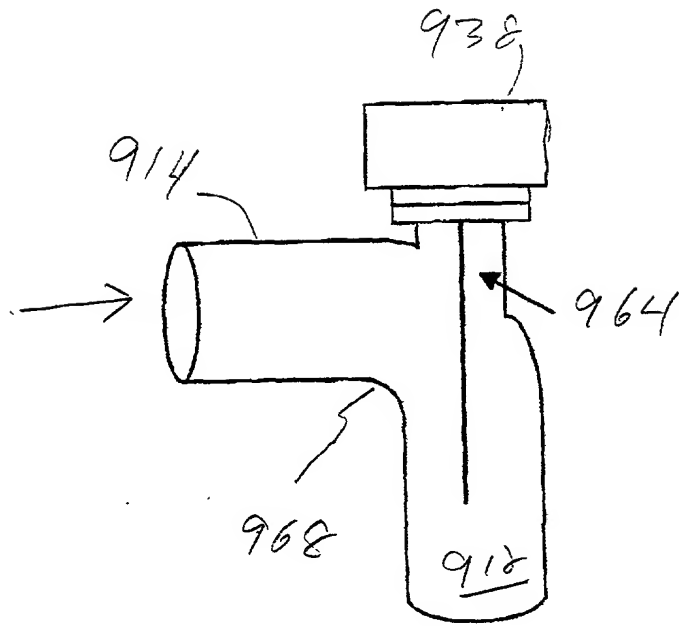


Fig. 22

1. The present invention relates to a system for measuring the dielectric constant of a material.

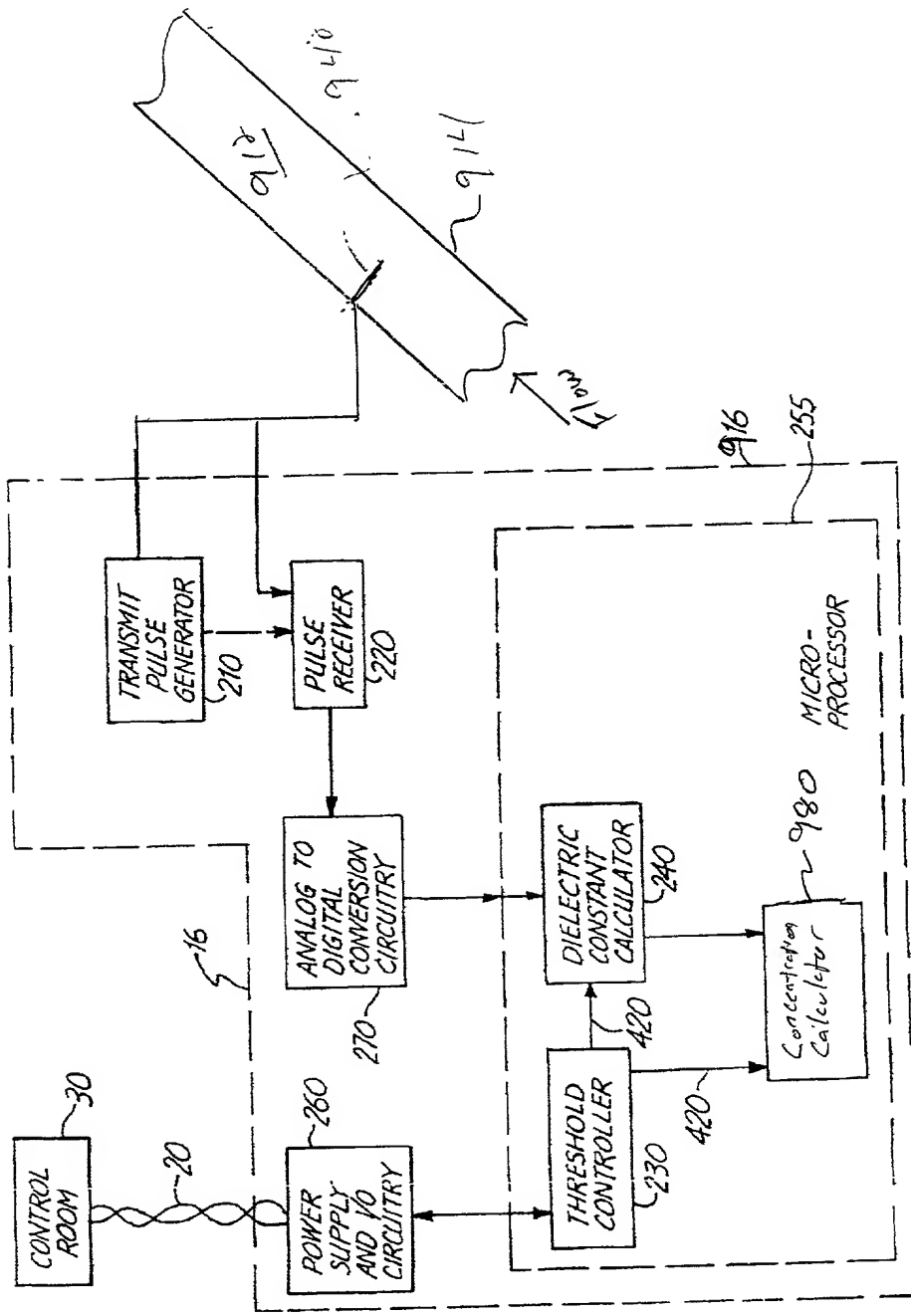


Fig. 23